

FIG. 1

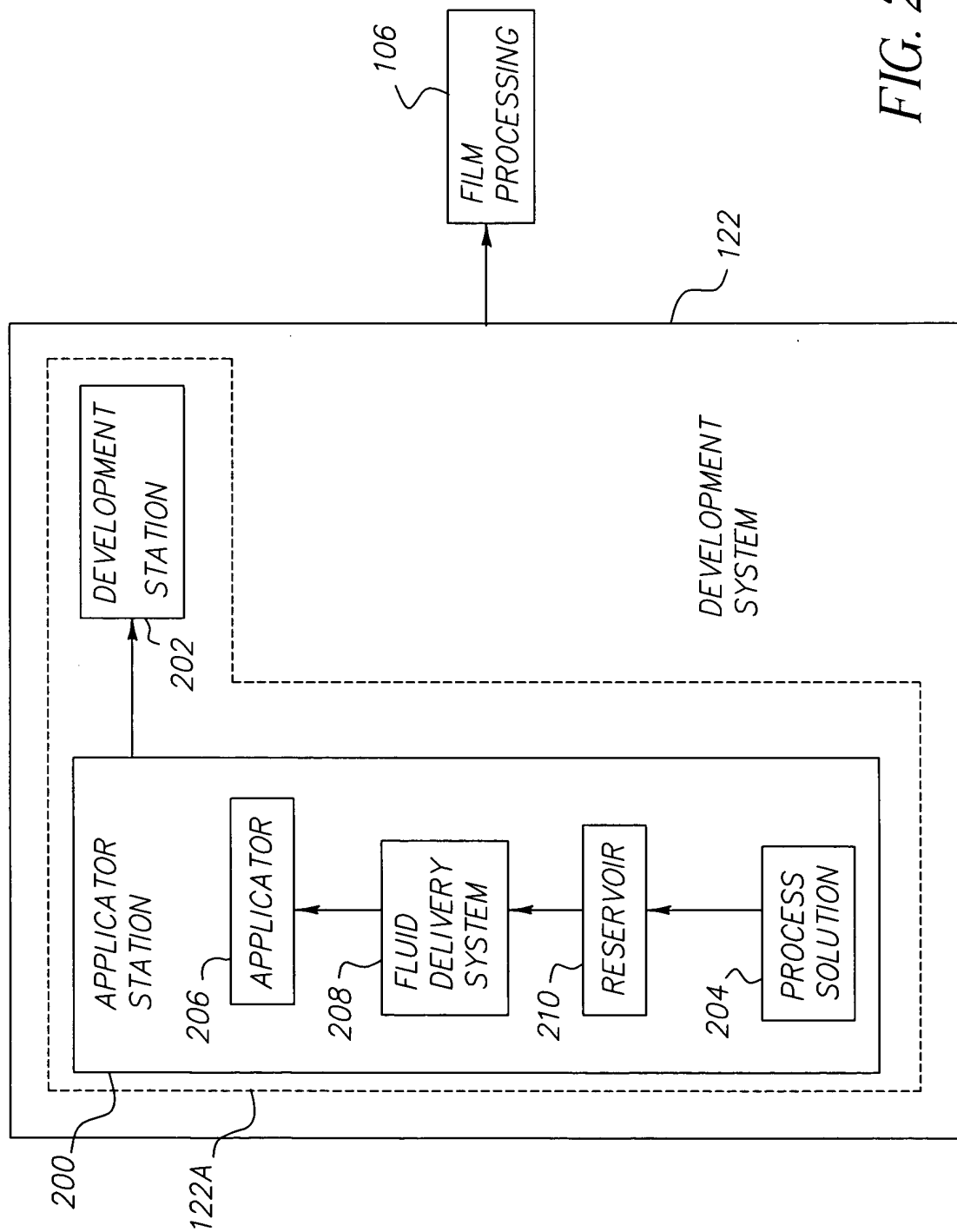


FIG. 2A

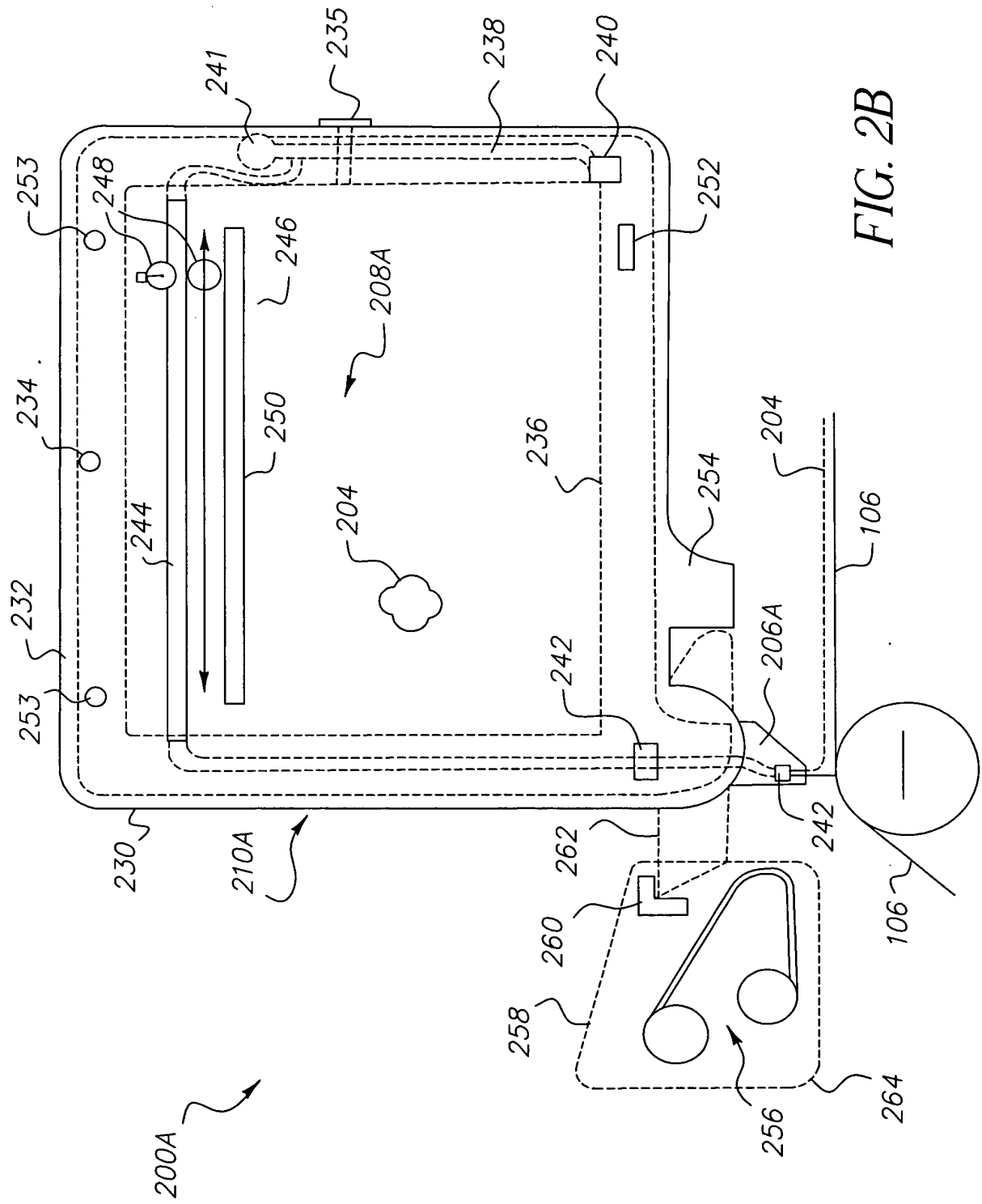


Figure 1 is a schematic diagram of a system for processing a substrate. The system includes a substrate 106 with a top surface 104 and a bottom surface 204. A processing chamber 206B is positioned above the substrate, containing a nozzle 208B and a gas inlet 210B. A gas supply system 222A is connected to the chamber, including a gas source 222A and a gas inlet 206A. A gas outlet 206B is also shown.

FIG. 2C-1

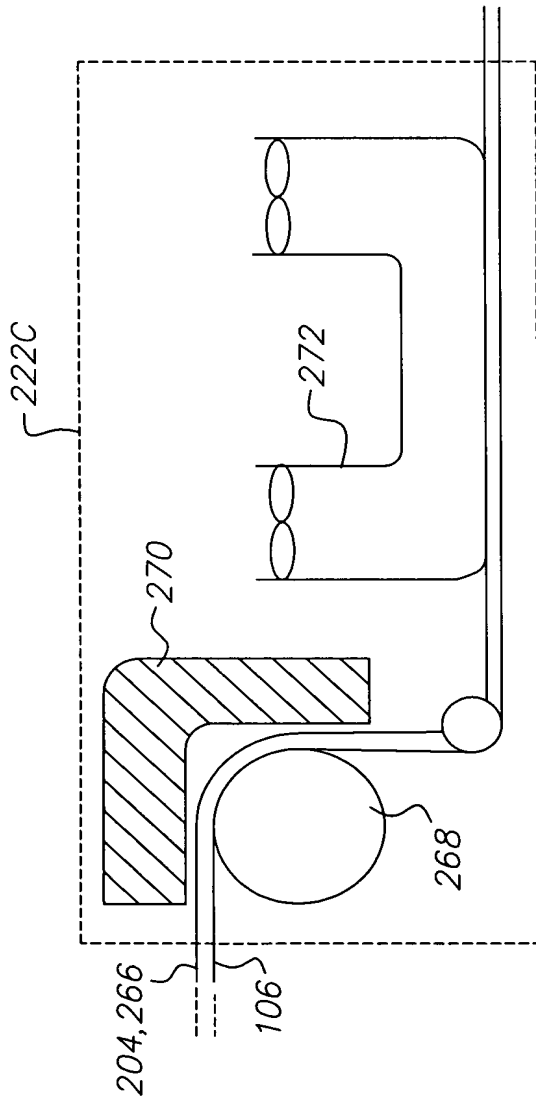


FIG. 2C-3

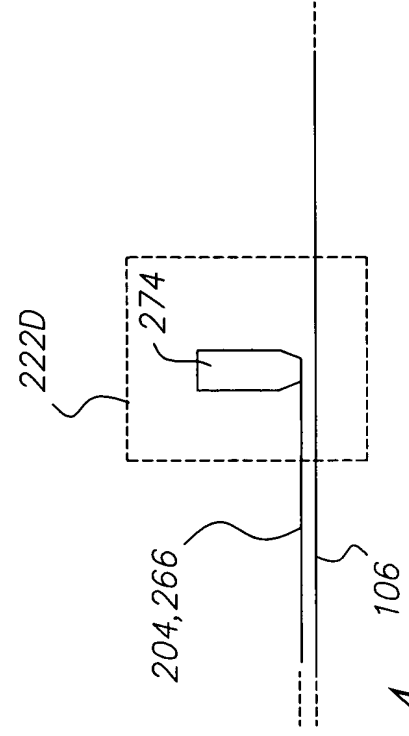


FIG. 2C-4

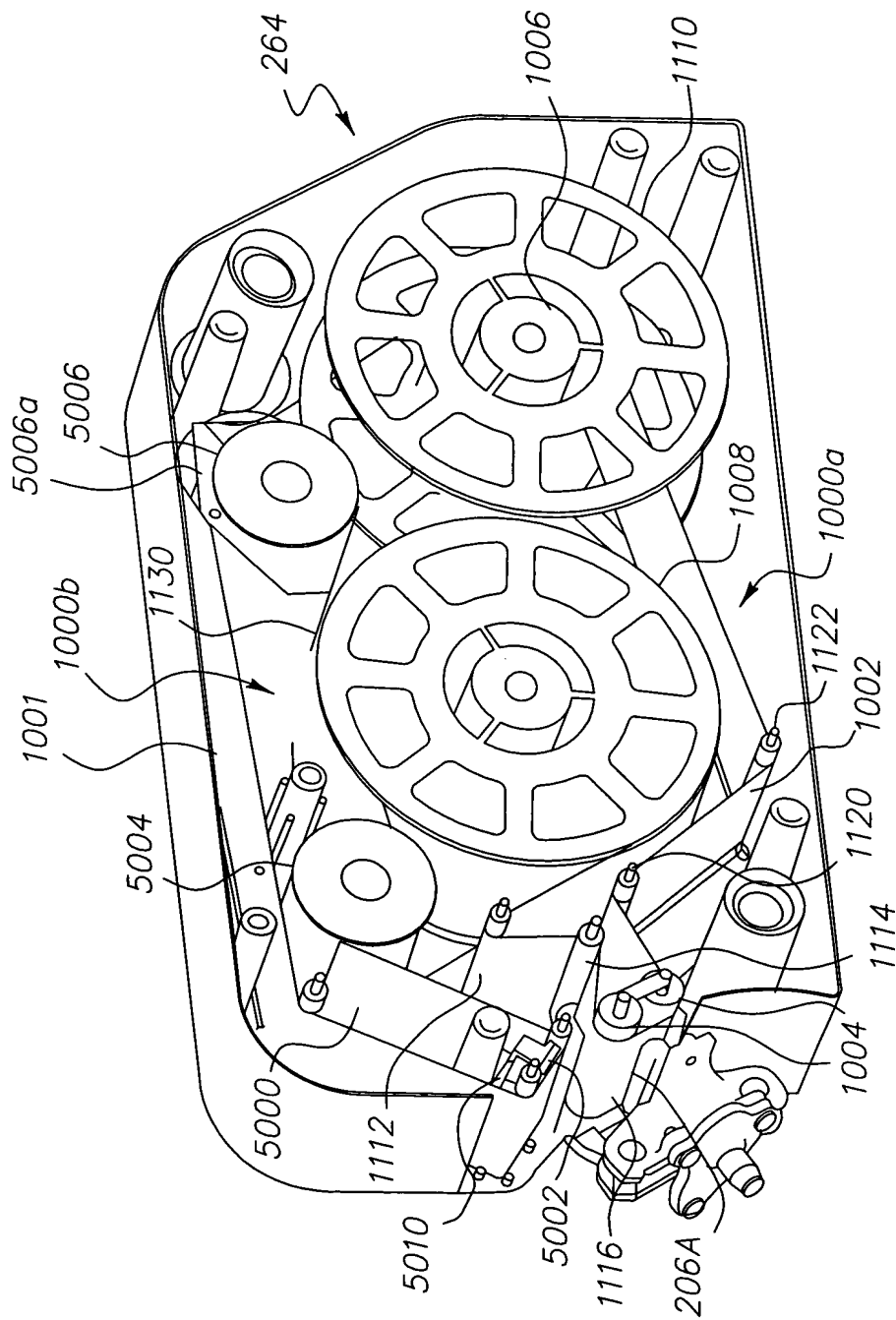


FIG. 3

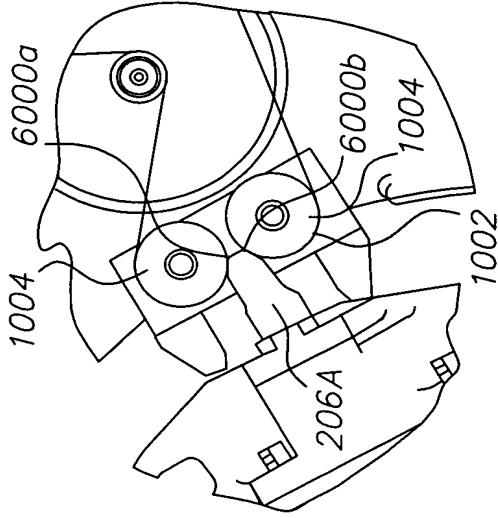


FIG. 4B

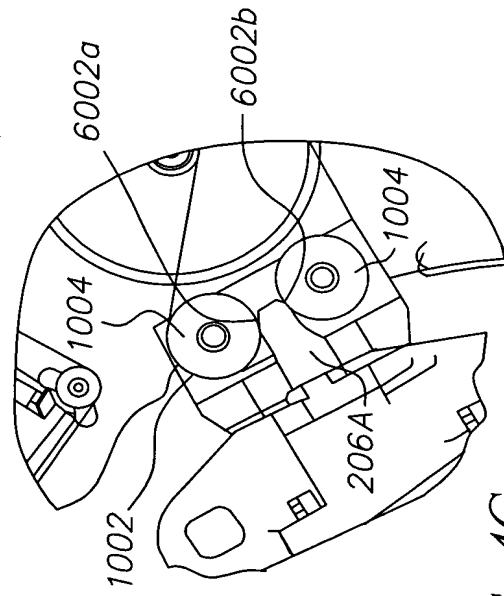


FIG. 4C

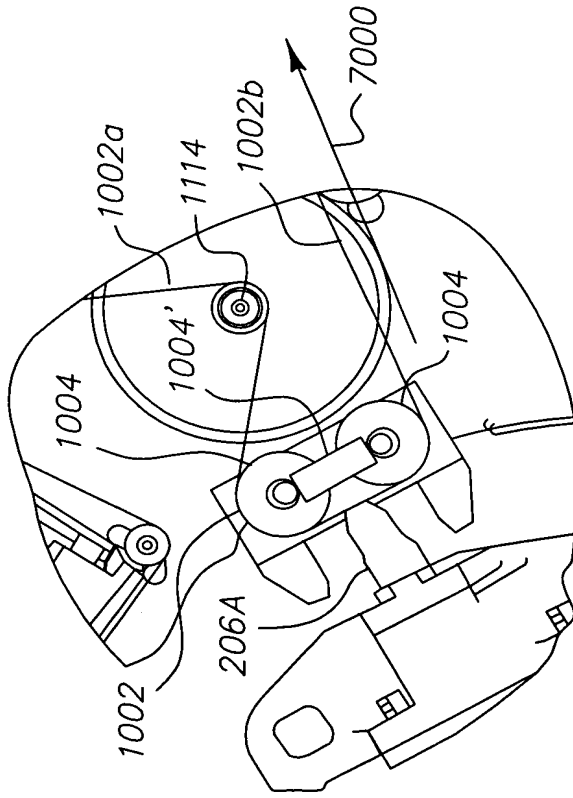


FIG. 4A

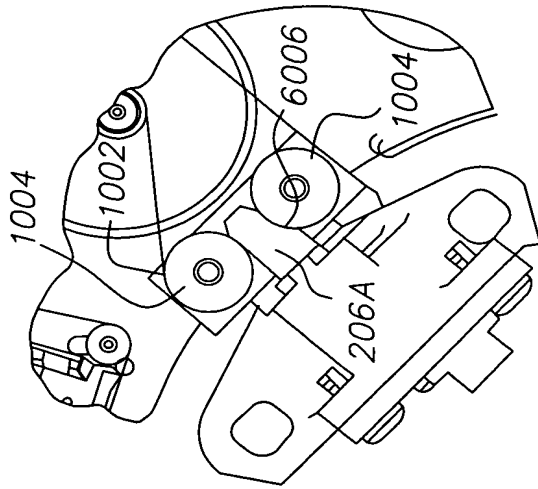


FIG. 4E

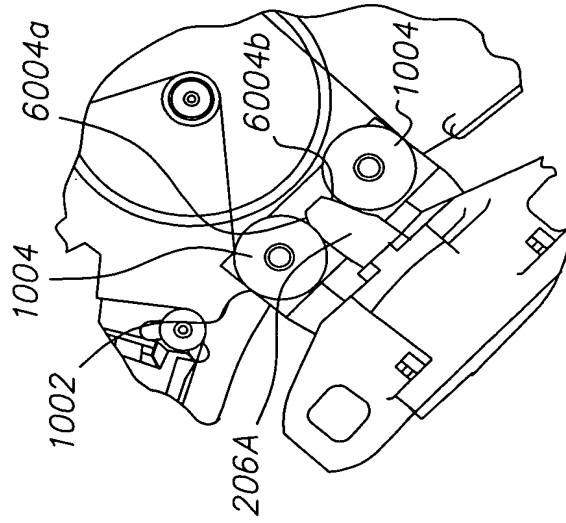


FIG. 4D

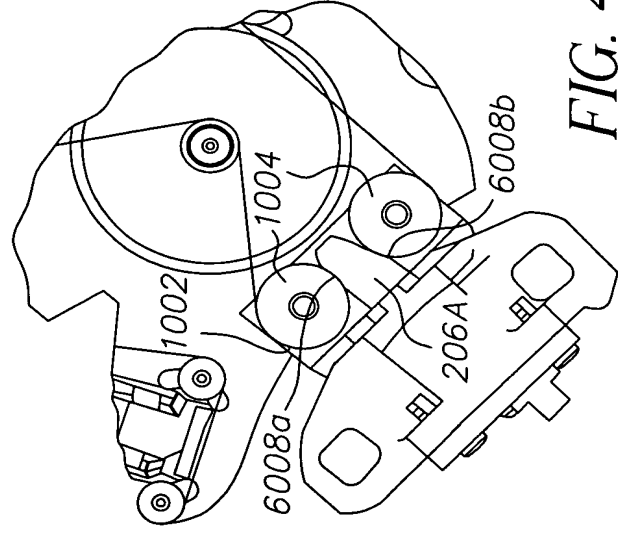


FIG. 4F



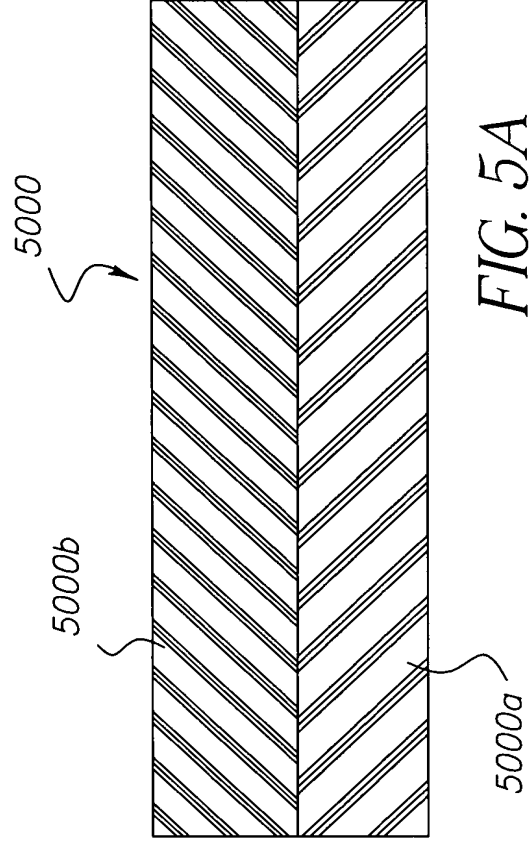


FIG. 5A

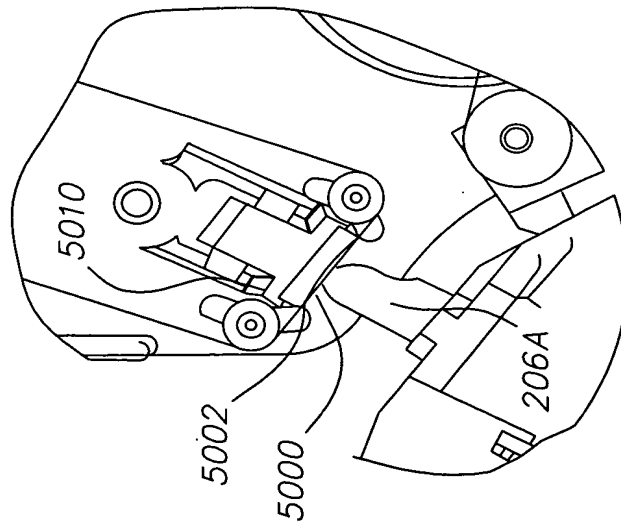


FIG. 5B

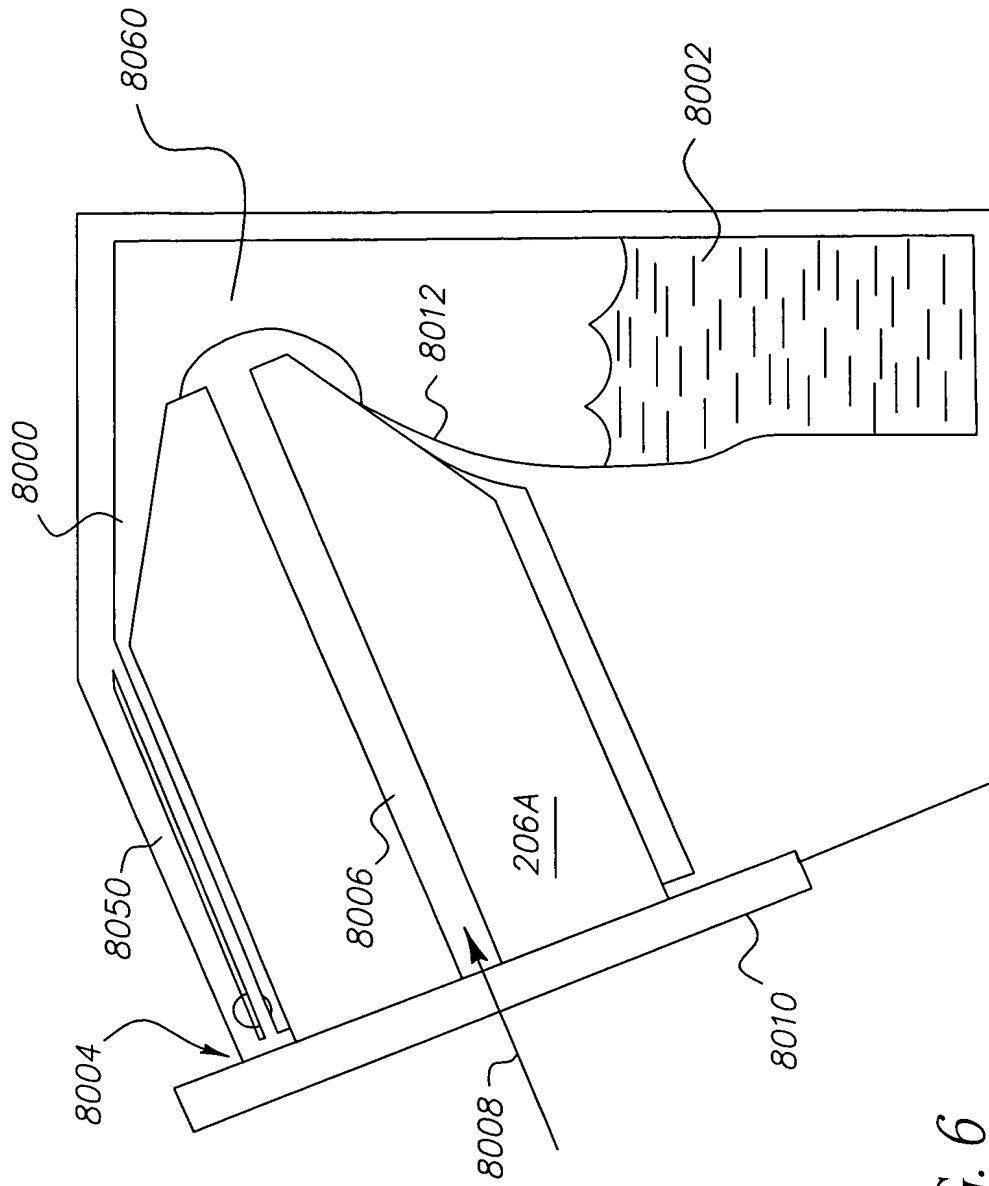


FIG. 6

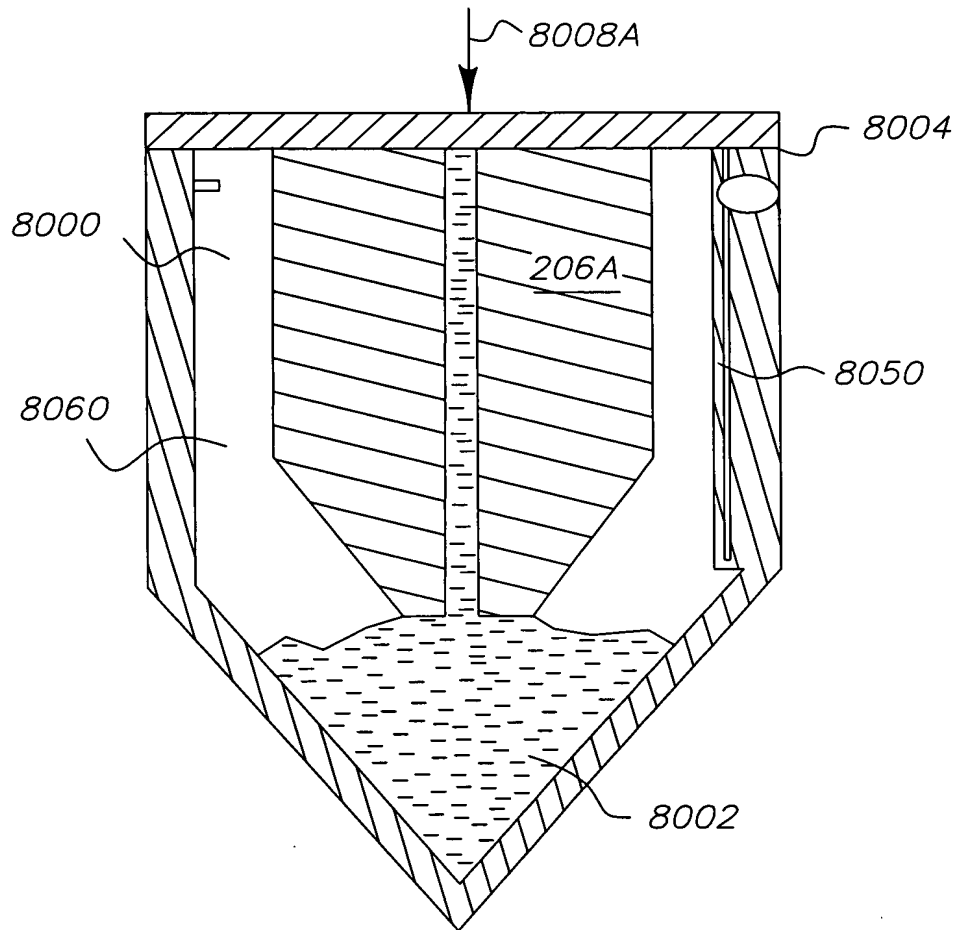


FIG. 7

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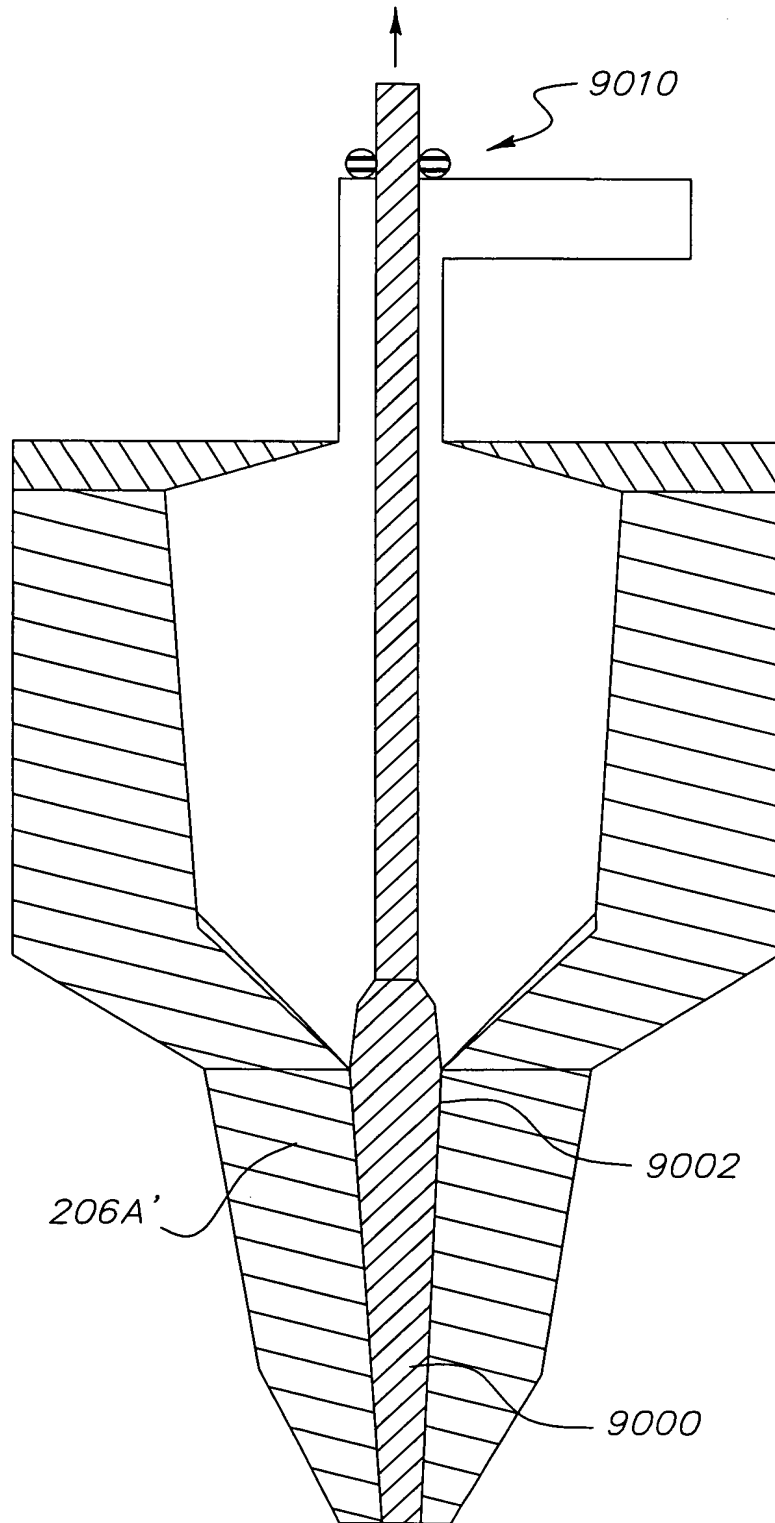


FIG. 8A

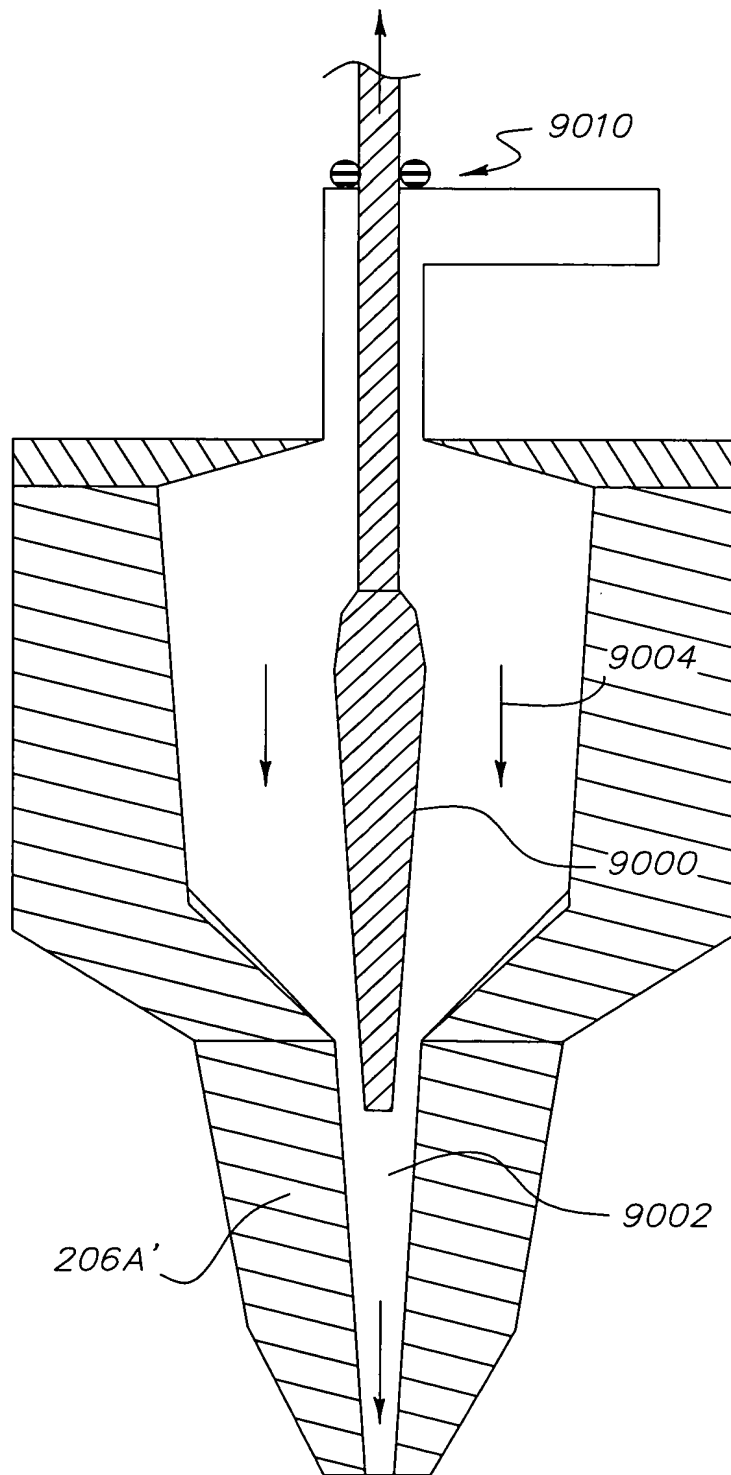


FIG. 8B